



### **AUTOMATIC PROBER**



#### PEGASUS™ A200 FEATURES

- High throughput cassette to cassette automation.
- Automatic wafer handling, pattern recognition and wafer probing.
- Wafer pre-alignment and wafer detection.
- Many automation options.

- Customizable product enhancing hardware and software options.
- Performance thermal chuck solutions.
- ✓ Wide range of product enhancing accessories.
- → Robust mechanical design.

## MEETING YOUR PROBING CHALLENGES



The Pegasus<sup>™</sup> A200 series offers dual-end, parallel processing of wafers which optimizes wafer handling for maximum throughput.

Designed for easy access when manually loading and unloading wafers the Pegasus<sup>™</sup> A200 has a capacity of two cassettes, each containing 25 wafers.

Featuring a highly advanced, single-stage wafer detection pre-alignment and transportation system, the Pegasus™ A200 ensures long-term accuracy and repeatability.

The Pegasus<sup>™</sup> A200 Series probers deliver menu-driven, push button control via proprietary LabMaster<sup>™</sup> control and monitoring software.

An extensive range of control and monitoring parameters enable users to operate Pegasus™ A200 Series probers at peak performance, including: realtime monitoring and test setup; yield analysis of both the wafer and batch under test; premium mapping capability; image analysis, and a host of other advanced features.

Configurable to voltages in excess of 5 kV for specialized applications

Optional thermal chuck capability.

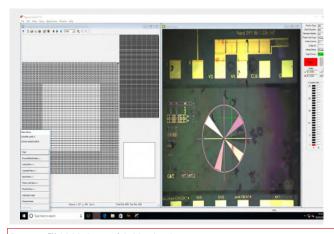


Pegasus™A200



# PATTERN RECOGNITION SYSTEM; ROBOT HANDLING SYSTEM; CONFIGURABLE TO VOLTAGES IN EXCESS OF 5 KV FOR SPECIALIZED APPLICATIONS; OPTIONAL THERMAL CHUCK CAPABILITY.

- ✓ Menu-driven, push button control.
- ✓ Real-time monitoring and test setup.
- ✓ Yield analysis of both the wafer and batch under test.
- Premium mapping capability.
- ✓ Probe to pad alignment for saw frame die.



Pegasus™ A200 Control & Monitoring



### SPECIAL HANDLING

Wentworth's Pegasus<sup>™</sup> A200 automatic prober for 2-inch to 8-inch wafers, is ideal for high volume, special handling applications such as GaAs, saw frames, ceramics and silicon.

PROBER	
XY STAGE	
Туре	High precision re-circulating ball screws
Stage Travel	210 mm x 210 mm (8.3" X 8.3")
Resolution	1.25 μm
Accuracy	± 7 μm over 200mm
Repeatability	± 4 µm
XY Speed	Up to 100 mm/s
Automatic Alignment Repeatability	± 5 μm

WAFER HANDLER	
ROBOT	
Speed	1270 mm/s (R), 254 mm/s (Z), 800 °/s (Ø)
Positional Repeatability	12.7 µm (Z), 38.1 µm (R) 0.01°(Ø) at constant temperature
Flat Orientation	Selectable
Pre-Alignment Accuracy	± 63.5 µm ± 0.125°
Repeatability	± 4 µm
XY Speed	Up to 100 mm/s

